ANNEALSYS

MC-050

2-inch MOCVD / RTP system In-situ annealing capability

APPLICATIONS

Metal and alloys, Oxides, Nitrides, III-V, II-VI, Nanotubes and nanowires, ...

- Semiconductor: SiO₂, HfO₂, Ta₂O₅, Cu, TiN, TaN
- Nitride and alloys: GaN, AIN, GaAs, GaAsN...
- High k Dielectric: SrTiO₃, BaTiO₃, Ba_(1-x)Sr_xTiO₃ (BST)
- Ferroelectric: SBT, SBTN, PLZT, PZT,...
- Superconductor: YBCO, Bi-2223, Bi-2212, Tl-1223, ...
- Piezoelectric: (Pb, Sr)(Zr,Ti)O₃, Modified Lead Titanate
- Colossal Magneto Resistance
- Nanotubes and nanowires
- Thermal coatings
- Mechanical coatings
- Optics
- Etc...

SPECIFICATIONS

The Annealsys MC050 is a 2-inch DLI-MOCVD / RTP reactor especially developed to meet the requirements of research and development units.

The MC050 allows doing deposition of oxides, nitrides, metals, III-V and II-VI on various types of substrates by MOCVD using diluted solid and liquid organometallic precursors.

The MC050 system can be provided with one or several direct liquid injection (DLI) vaporizers allowing the widest range of utilization of precursors for development of new materials.

Glove box loading version is available as an option.

The infrared lamp heating system provides in-situ annealing process capability inside the deposition chamber.

PERFORMANCE CHARACTERISTICS

- Temperature range: RT to 1200 C
- Up to 6 vaporizers
- Vacuum range: Atmosphere to 10-3 Torr



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ANNEALSYS

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Maximum substrate diameter 2-inch (51 mm)

Process chamber Quartz tube with water-cooled stainless steel flanges

Heating Halogen lamps

Temperature control Thermocouple temperature control

Digital PID temperature controllers

Vacuum, gas and liquid Purge gas line with needle valve

Up to 6 process gas lines with mass flow controllers

Up to 6 vaporizer units selected function of liquid precursors

Custom liquid panel depending on the application

Vacuum valve and vacuum gauge Optional vacuum rotary pump

Optional pressure control with throttle valve

Control Full PC control

Facilities Electricity: 3x400V+N+Gr or 3x220V+Gr, 50/60 Hz

Power: 20 kW

Water: 2 to 6 bars, pressure drop 1 bar, 8 l/mn

Compressed air: 6 bars (valve actuation)

Process gas fittings: Swagelok ¼ (Optional VCR)

Dimensions and weight Width: 955 mm

Depth: 1812 mm

Height: 1604 mm

Weight: 400 kg

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